

**MRS SYMPOSIUM OO**

Volume 1801 • 2015 MRS Spring Meeting

# Metal-Assisted Chemical Etching of Silicon and Other Semiconductors

EDITORS

Owen Hildreth

Xiuling Li

Zhipeng Huang

Konrad Rykaczewski

**CAMBRIDGE**

A publication of the

**MRS** MATERIALS RESEARCH SOCIETY®  
*Advancing materials. Improving the quality of life.*

# MRS Online Proceedings Library

## Editorial Board

### Editorial Board Chair:

Michelle L. Oyen, *Cambridge University, United Kingdom*

### Editorial Board Members:

David Bahr, *Purdue University, USA*

Asa Barber, *Queen Mary University of London, United Kingdom*

Frank del Rio, *National Institute of Standards and Technology, USA*

Marilyn L. Minus, *Northeastern University, USA*

Roger Narayan, *North Carolina State University, USA*

The *MRS Online Proceedings Library* (ISSN: 1946-4274) features over 100,000 peer-reviewed papers presented at MRS Meetings. The proceedings papers can be viewed by meeting or topic, and are fully searchable.

**Manuscripts:** Information on article submission may be found at the *MRS Online Proceedings Library* homepage at <http://journals.cambridge.org/opl>.

**Subscriptions:** Institutions and libraries which are not current customers may purchase a 12-month unlimited access package to all MRS proceedings volumes/papers that are available online. To find out how to purchase OPL please contact: [online@cambridge.org](mailto:online@cambridge.org), in the Americas, or [library.sales@cambridge.org](mailto:library.sales@cambridge.org), in the rest of the world.

**Copyright © 2015**, Materials Research Society. All rights reserved. No part of this publication may be reproduced, in any form or by any means, electronic, photocopying, or otherwise, without permission in writing from Cambridge University Press. Policies, request forms and contacts are available at: <http://www.cambridge.org/rights/permissions/permission.htm>. Permission to copy (for users in the USA) is available from Copyright Clearance Center <http://www.copyright.com>, email: [info@copyright.com](mailto:info@copyright.com).

**MATERIALS RESEARCH SOCIETY  
SYMPOSIUM OO VOLUME 1801**

# **Metal-Assisted Chemical Etching of Silicon and Other Semiconductors**

Symposium held April 6-10, 2015, San Francisco, California, U.S.A.

## **EDITORS**

**Owen Hildreth**

Arizona State University  
Tempe, Arizona USA

**Xiuling Li**

University of Illinois  
Urbana, Illinois USA

**Zhipeng Huang**

Jiangsu University  
Jiangsu, China

**Konrad Rykaczewski**

Arizona State University  
Tempe, Arizona USA



Materials Research Society  
Warrendale, Pennsylvania



ISSN: 1946-4274

# CONTENTS

<b>* Uniform Metal-assisted Chemical Etching and the Stability of Catalysts</b> .....	<b>1</b>
Liyi Li, Colin M. Holmes, Jinho Hah, Owen J. Hildreth, and Ching P. Wong	

\*Invited Paper